IN THE CLAIMS

- 1. (Currently Amended) A mesoporous silica film prepared from a surfactant containing solution, having a dielectric constant less than 3 that has both a relative stability, wherein a dielectric constant increases no more than approximately 20% when the film is taken from an equilibrated condition of 0.0% relative humidity or vacuum to an equilibrated condition of 50% relative humidity, and an absolute stability, wherein the dielectric constant remains less than 3 under any conditions including humid conditions of at least 40% relative humidity, in a humid atmosphere, a film thickness from about 0.1 µm to about 1.5 µm, and an average pore diameter less than or equal to about 20 nm.
- 2. (Previously Presented) The mesoporous silica film as recited in claim 1, wherein said average pore diameter is less than or equal to about 10 nm.
- 3. (Previously Presented) The mesoporous silica film as recited in claim 1, wherein said thickness has a standard deviation less than +/- 5%.
- 4. (Currently Amended) The mesoporous silica film as recited in claim 1, wherein the porosity of said mesoporous silica film is disordered, lacking a regular geometric arrangement of pores, and characterized by an x-ray diffraction peak between about 0.75 and about 2 degrees 2-theta or by the absence of an x-ray diffraction peak in the range from 2-6 degrees 2-theta.
 - (Canceled)
 - 6. (Canceled)
 - (Canceled)
 - (Canceled)
 - 9. (Canceled)
 - 10. (Canceled)

(Canceled)

12-52 previously cancelled as non-elected claims.

53. (Currently Amended) A mesoporous silica film characterized by:

a disordered porosity, lacking a regular geometric arrangement of pores, and characterized by an x-ray diffraction peak between about 0.75 and about 2 degrees 2-theta or by the absences of an x-ray diffraction peak in the range of 2-6 degrees 2-theta;

a dielectric constant less than 3.0 that is stable, wherein a stable film has at least one of either relative stability, wherein a dielectric constant increases no more than approximately 20% when the film is taken from an equilibrated condition of 0.0% relative humidity or vacuum to an equilibrated condition of 50% relative humidity, or absolute stability, wherein the dielectric constant remains less than 3 under any conditions including humid conditions of at least 40% relative humidity;

a film thickness from about 0.1 μm to about 1.5 μm; and an average pore diameter less than or equal to about 20 nm.

54. (Canceled)

55. (Currently Amended) A mesoporous film characterized by:

a dielectric constant less than 3.0 that is stable, wherein a stable film has at least one of either relative stability, wherein a dielectric constant increases no more than approximately 20% when the film is taken from an equilibrated condition of 0.0% relative humidity or vacuum to an equilibrated condition of 50% relative humidity, or absolute stability, wherein the dielectric constant remains less than 3 under any conditions including humid conditions of at least 40% relative humidity;

a film thickness from about 0.1 μ m to about 1.5 μ m; and an average pore diameter less than or equal to about 20 nm.

57-65 previously cancelled as non-elected claims.

(Canceled)

- 67. (Original) A mesoporous film having a thickness from about 0.2 μm to about 1.5 μm and a standard deviation about said thickness that is less than +/- 5%.
 - 68. (Canceled)
 - 69. (Canceled)
 - 70. (Canceled)
- 71-74 previously cancelled as non-elected claims.
- 75. (Currently Amended) A surfactant-templated <u>dehydroxylated</u> mesoporous dielectric film on a substrate prepared from a silica precursor solution by evaporation, wherein the film is characterized by disordered porosity, <u>lacking a regular geometric</u> arrangement of pores, and characterized by an x-ray diffraction peak between about 0.75 and about 2 degrees 2-theta or by the absences of an x-ray diffraction peak in the range of 2-6 degrees 2-theta:
- 76. (Currently Amended) The dielectric film of claim 751, wherein the silica precursor solution includes one or more of methyl and ethyl groups.
- 77. (Currently Amended) The dielectric film of claim 751, wherein the silica precursor solution includes one or more of alkyl and phenyl groups.
- 78. (Currently Amended) The dielectric film of claim 754, wherein the silica precursor solution includes carbon-containing groups.
- 79. (Previously Presented) A dehydroxylated mesoporous silica film prepared from a surfactant containing silica precursor solution, wherein dehydroxylation of the porous film comprises the following steps:
 - a. exposing said porous film to a silane;
 - b. removing gas-phase and physisorbed species from said porous film.

- 80. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 75 79, wherein steps (a) and (b) are performed at least once.
- 81. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 75 22, wherein said gas-phase species and said physisorbed species are removed from said porous film by applying a vacuum on said porous film.
- 82. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 76 80 wherein said gas-phase species and said physisorbed species are removed from said porous film by applying a vacuum on said porous film.
- 83. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 75 79, wherein said gas-phase species and said physisorbed species are removed from said porous film by applying a flowing forming gas or inert gas.
- 84. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 76 80, wherein said gas-phase species and said physisorbed species are removed from said porous film by applying a flowing forming gas or inert gas.
- 85. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 75 79 wherein said surfactant containing silica precursor solution comprises alkylsubstituted silica precursors.
- 86. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 76 80, wherein said surfactant containing silica precursor solution comprises alkylsubstituted silica precursors.
- 87. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 77.81, wherein the surfactant containing silica precursor solution comprises alkyl-substituted silica precursors.
- 88. (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 78 82, wherein the surfactant containing silica precursor solution comprises alkylsubstituted silica precursors.

- (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 79 83, wherein the surfactant containing silica precursor solution comprises alkylsubstituted silica precursors.
- (Currently Amended) A dehydroxylated mesoporous silica film as recited in claim 80 84, wherein the surfactant containing silica precursor solution comprises alkylsubstituted silica precursors.
- 91. (New) The mesoporous silica film as recited in claim 1, wherein the silica precursor solution includes carbon-containing groups.
- 92. (New) The mesoporous film as recited in claim 55, wherein the precursor solution includes carbon-containing groups.